

## PROCESSING SOLUTION FEEDING METHOD AND DEVICE

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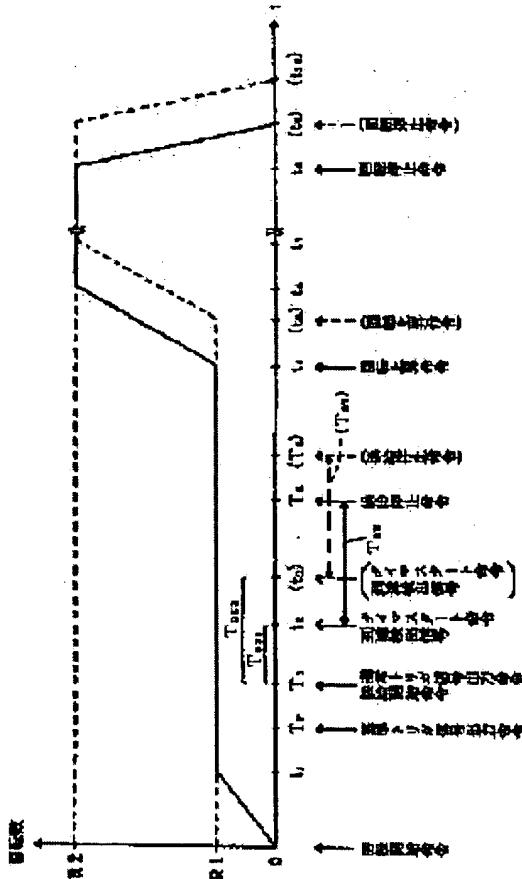
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### Abstract of JP9270373

PROBLEM TO BE SOLVED: To execute a feed start command and execute the later commands according to the arrival of a processing solution at a substrate.

SOLUTION: A substrate is spin-driven to reach a revolution per minute  $R_1$  at the time  $t_1$  by the spin starting command so that a feed starting command may be executed at a time  $T_s$  to start feeding a photoresist solution at a specific flow rate. Next, at the time point of  $t_2$  detecting the arrival of the photoresist solution at the surface of the substrate, the timer starting command counting the elapse time is executed so as to execute the feed stopping command at the time point of arriving at the feed time  $T_{s1}$  (time TE) to stop feeding the photoresist solution. Finally, at the time  $t_4$ , by executing a spin rising command, the revolution per minutes can be accelerated so that the substrate may arrive at the revolution per minutes  $R_2$  at the time  $t_6$  to execute the spin stopping command at the time  $t_8$  further to finish the coating step at the time  $t_9$ .



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